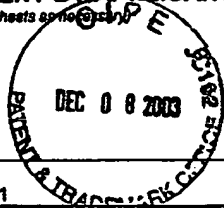


Substitute for form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

**Complete if Known**

Application Number	10/081,818
Filing Date	February 20, 2002
First Named Inventor	Eldridge, Jerome
Group Art Unit	2818
Examiner Name	Ho, Tu-Tu

Sheet 1 of 1

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EXAMINER

Tu-Tu Ho

DATE CONSIDERED

Jan 2004

Substitute Disclosure Statement Form (PTO-1449)

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 808. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.